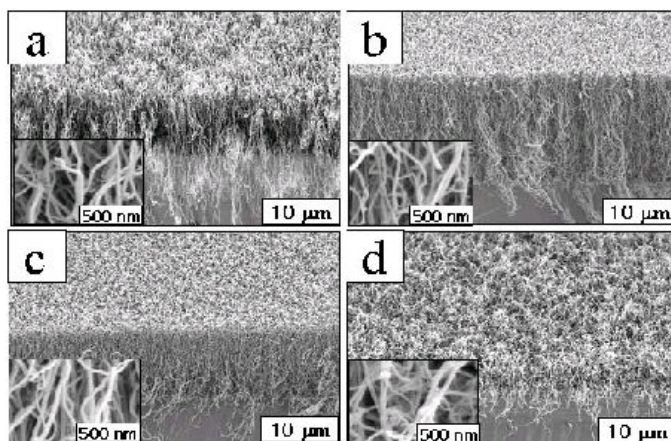
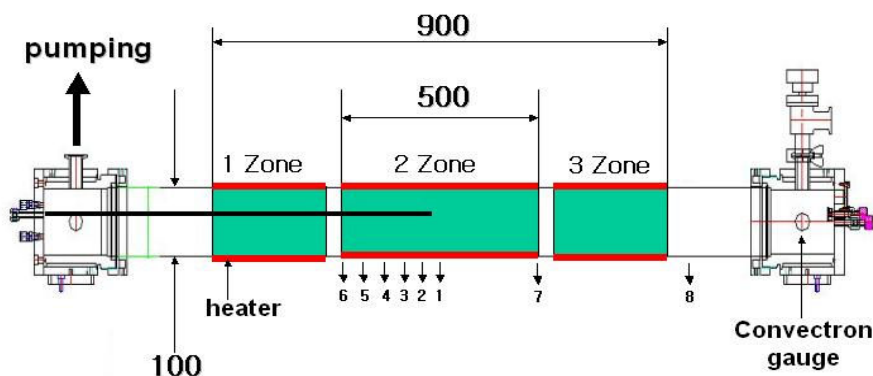


ATS-CVD Series Thermal CVD System with Uniform Heating Zone



SEM images of CNTs grown on Ni layers deposited by sputtering at (a) 25°C, (b) 300°C, (c) 400°C, (d) 500°C

◇ Temperature Uniformity



2nd zone area temp uniformity : 0.6~1.0% (at 650, 800, 950°C)

◇ Special Features

◆ Applications

R&D or small scale of production system for multiwall and single wall CNTs

◆ Tubular furnace type of thermal CVD system with highly uniform heating zone

◆ Dimension

800L × 1450H × 600W (mm³)

◆ Others

Power: 220V, 25A

Gas : H₂/C₂H₂(C₂H₄, CH₄, CO)/Ar

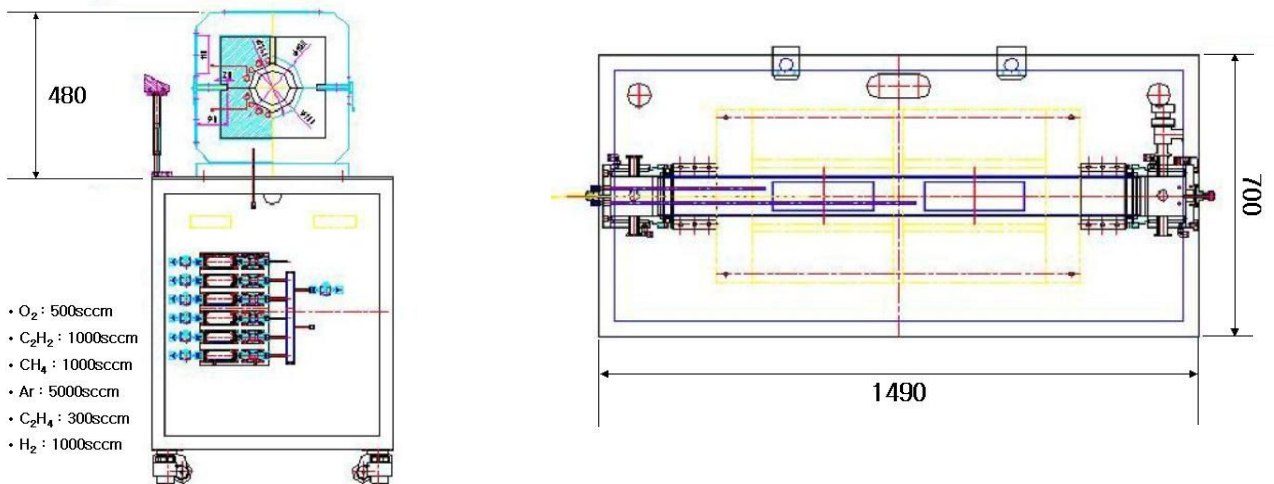
Furnace heater : nichrome or kanthal A1

(heating rate : max 30°C/min,

max. temp.: 1200±3°C)

Pump : rotary(600l/min)

◇ Layout



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